Sheet <u>1</u> of <u>3</u>

Substitute Form PTO-1449 (Modified)		Attorney's Docket No. 05770-156001	Application No. 09/855,312	
by A	closure Statement O / 6	Applicant Martin W. Rupich et al.		
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	AB	3,985,281	10/12/76	Diepers et al.	1			1		
	AC	4,442,396	04/10/84	Hucker				1		
	. AD	4,659,973	04/21/87	Stich	$\top 1$			1		
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	AF	5,038,127	08/06/91	Dersch						
	AG	5,071,828	12/10/91	Greuter et al.				•		
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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 05770-156001	Application No. 09/855,312
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Che	AAA	WO 97/05669	02/13/97	WIPO				
UMD	ABB	WO 98/58415	12/23/98	WIPO				
CM	ACC	WO 99/16941	04/08/99	WIPO				
m	ADD	WO 99/17307	04/08/99	WIPO				
pm	AEE	WO 99/25908	05/27/99	WIPO				
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ans	ATT	Sheth, Atul et al., "Bench Scale Evaluation of Batch Mode Dip-Coating of Sol-Gel LaAIO ₃ Buffer Material", <i>IEEE Transactions on Applied Superconductivity</i> , Vol. 9, No. 2 June 1999, pp. 1514-1518				
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ONS	AA	4,859,652	08/22/89	Block			
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Sheet <u>1</u> of <u>1</u> Application No. 09/855,312

Form PTO-1449

U.S. Department of Commerce Patent and Trademark Office Attorney's Docket No. 05770-156001

Information Disclosure Statement by Applicant (Use several sheets if necessary)

Applicant

Martin W. Rupich et al.

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(37 CFR §1.98(b))

May 14, 2001

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